

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,803,534 B1
DATED : October 12, 2004
INVENTOR(S) : Shea Chen et al.

Page 1 of 1

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

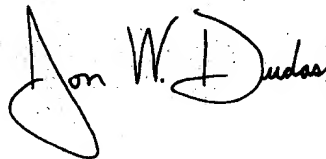
Title page.

Item [57], **ABSTRACT**, should read:

-- A micro-electro-mechanical switch (10, 110, 210) is known as a MEMS, and includes a base section (13, 14, 17-18) having two spaced conductive posts (17, 18). A conductive part (22) is provided between the posts, and is covered by a dielectric layer (23). A membrane (31, 131, 231) extends between the posts and has spaced expansion sections (41-42, 141-142, 241-242) which facilitate lengthwise expansion of the membrane as it flexes between positions in which a central portion thereof is respectively spaced from and engaging the dielectric layer. A method of making the switch includes providing a spacer material (76, 176, 177, 178) with a top surface having grooves or ridges that correspond to the expansion sections, depositing the membrane over the top surface of the spacer, and then removing the spacer material. --.

Signed and Sealed this

Eleventh Day of April, 2006

A handwritten signature in black ink, reading "Jon W. Dudas". The signature is stylized, with a large loop for the "J" and a cursive "Dudas".

JON W. DUDAS

Director of the United States Patent and Trademark Office